Paper List

January ―December, 2026

E2026-1(C) Statistical Capacitance Measurement of Si Trench Capacitors Using 3D Stacked Array Test Circuit
IEEE 38th International Conference on Microelectronic Test Structures, (ICMTS2026), pp.7-11, March 23-26, (2026) , Matsue, Japan
Ryoya Nishimaki, Koga Saito, Takezo Mawaki, Rihito Kuroda

E2026-2(C) A 72-dB SNR 1K-fps global shutter CMOS image sensor with dual pixel reset voltage and programmable gain amplifier
Society for Imaging Science and Technology,
Vol.38,ISS-288,pp.288-1-288-7,March, Electronic Imaging (2026), San Francisco, US
Kota Ogino, Takezo Mawaki, Rufuto Koba, Ken Miyauchi, Yushi Sakai, Rihito Kuroda
DOI: 10.2352/EI.2026.38.6.ISS-288

E2026-3(C) A Global Shutter Proximity Capacitance CMOS Image Sensor for High-precision and High-speed Capacitance Imaging
Society for Imaging Science and Technology,
Vol.38,ISS-289,pp.289-1-289-6,March, Electronic Imaging (2026), San Francisco, US
Hiroto Ogura, Ukyo Kotake, Takezo Mawaki, Ken Miyauchi, Rihito Kuroda
DOI: 10.2352/EI.2026.38.6.ISS-289

E2026-4(C) [Invited Paper]
Beyond Image Quality: Violet-Light–Enabled Displays for Visual Health
Society for Information Display International Symposium DISPLAY WEEK, pp.902-905,65-1, May 7th (2026), Los Angeles, US
Kazuo Tsubota, Takahiro Ishinabe, Yasuyuki Shirai, Koichi Kajiyama, Keisuke Mitsuoka

E2026-5(F) Band-gap formation in a one-dimensional periodic lattice: An alternative to the Bragg diffraction model
Materials Today Communications 56 (2026) 116194, 21 September 2026
Koichi Kajiyama
https://doi.org/10.1016/j.mtcomm.2026.116194

E2026-6(C) Development of Advanced High Dynamic Range CMOS Image Sensor Technologies
ITE Transactions on Media Technology and Applications (MTA), VOL.14, No.4, pp.171-180, October 2026
Ken Miyauchi
DOI: https://doi.org/10.3169/mta.14.171